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PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10078720	FILING DATE 02/19/2002	CLASS 219	SUBCLASS 1212	GAU 1725	EXAMINER Elve
<p>**APPLICANTS: Ye Kaidong; An Chengwu; Hong Minghui; Lu Yongfeng.</p> <p>**CONTINUING DATA VERIFIED:</p> <p>** FOREIGN APPLICATIONS VERIFIED:</p>					
PG-PUB <input type="checkbox"/> DO NOT PUBLISH <input type="checkbox"/>		RESCIND <input type="checkbox"/>		ATTORNEY DOCKET NO	
Foreign priority claimed <input type="checkbox"/> yes <input checked="" type="checkbox"/> no		35 USC 119 conditions met <input type="checkbox"/> yes <input checked="" type="checkbox"/> no		4795-004	
Verified and Acknowledged Examiners's initials <i>KE</i>		TITLE : Method and apparatus for cutting a substrate using laser irradiation			
U.S. DEPT. OF COMMERCE PAT & TM PTO-425 (Rev. 12-94)					

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
ISSUE FEE		Total Claims	Print Claim for O.G.
Amount Due	Date Paid	DRAWING	
Assistant Examiner		Sheets Drawg.	Figs. Drawg.
Primary Examiner		Print Fig.	
<input type="checkbox"/> TERMINAL DISCLAIMER		Application Examiner	
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